

Assay Characterization of CMP Slurries based on Densitometry, Refractive Index and Dynamic Light Scattering

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- **Experimental Apparati and Calibration Tests**

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 - ❖ **Densitometry**
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 - ❖ **Characterization of Spent Slurry Fujimi PL-7106**
 - ❖ **Summary of Phase II**

Problem Statement

- As the error margin in CMP decreases, slurries must meet stricter specifications and their components must be monitored tightly not only at POM&D but also at POU:
 - ❖ Physical parameters – Uniform PSD and minimal agglomeration and settling.
 - ❖ Chemical parameters – Uniform and optimal concentrations of UPW and additives (such as H₂O₂).
- Upstream of polishers slurry properties may vary due to issues with slurry handling and blending processes → **May affect process performance.**
- Densitometry has become the standard metrology tool for incoming slurry monitoring at POU.
- Inline Refractive Index (RI) measurement is another option → **Higher precision.**

Motivation and Goal

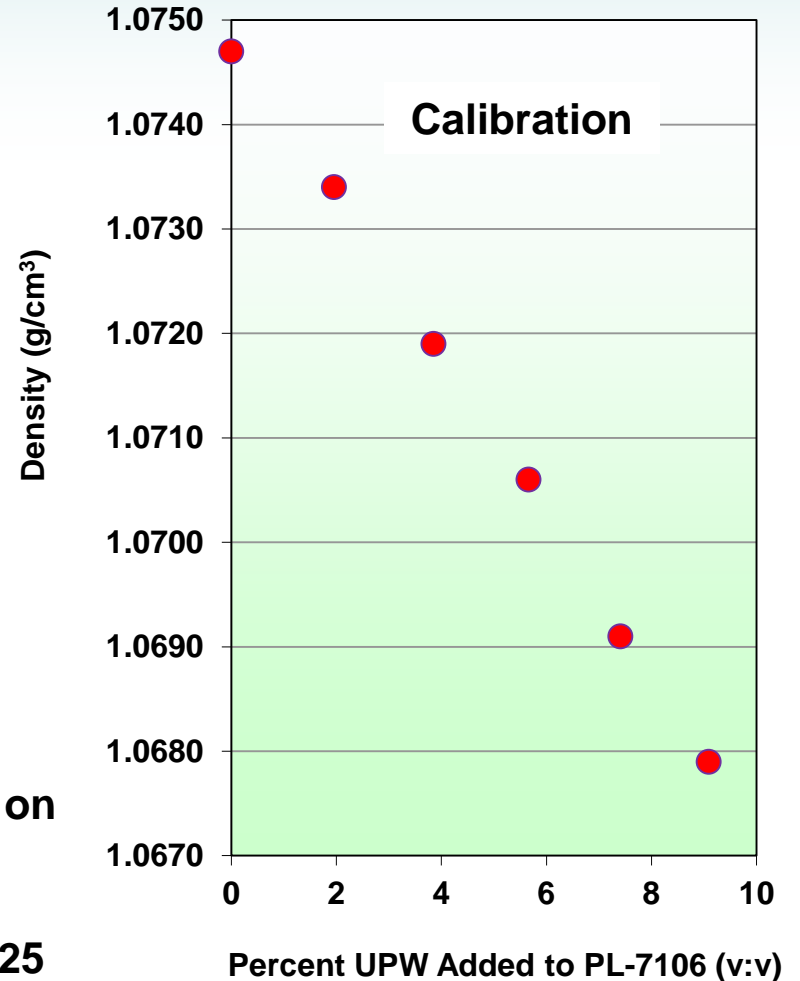
- Investigate the **correlation between RI and density** for 3 different slurries in a flow loop where small amounts of UPW are added to systematically alter the concentration.
- Compare the **smallest detectable change of both metrology tools** to show whether RI can be used to monitor smaller changes in the incoming slurry concentration → More accurate and precise data on slurry composition.
- Employ **dynamic light scattering** to detect whether there may be unexpected changes in average particle size as a function of dilution → **An indicator of agglomeration or changes in the slurry properties that may affect RI.**

**Preliminary Calibration Tests Using
Fujimi PL-7106 Copper Slurry
without H₂O₂**

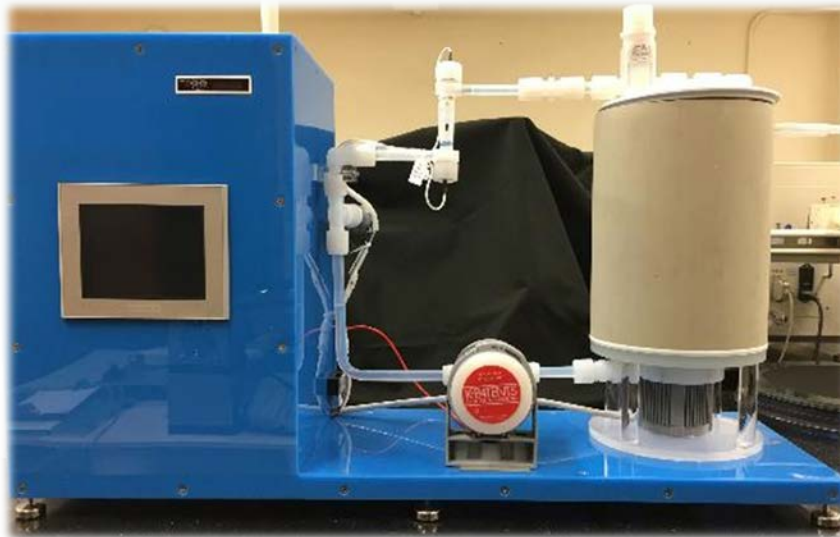
Offline Mettler Toledo Densito 30PX



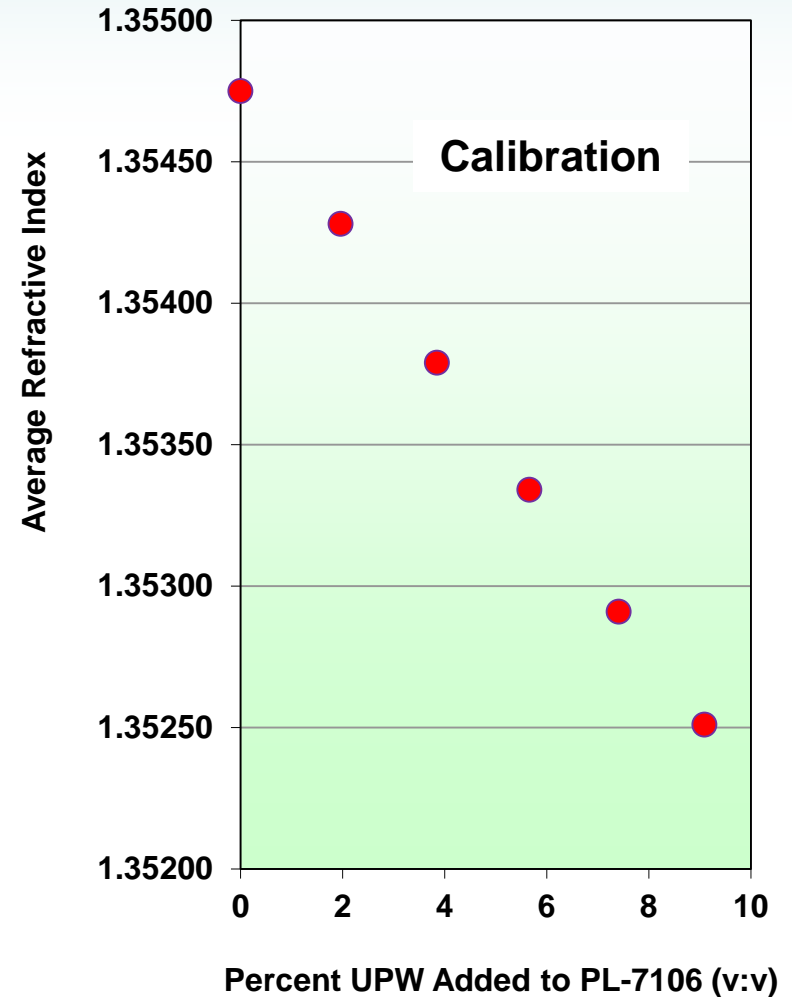
- Digital density measurement is based on a oscillating U-tube.
- Reported values are automatically adjusted to a baseline temperature of 25 °C.
- Precision = 10^{-4} g/cm³



Inline K-Patents Semicon Process Refractometer



- Flow loop was set at 6,500 ml/min.
- RI was measured continuously for 1 minute at 0.33 Hz.
- Precision = 10^{-5}



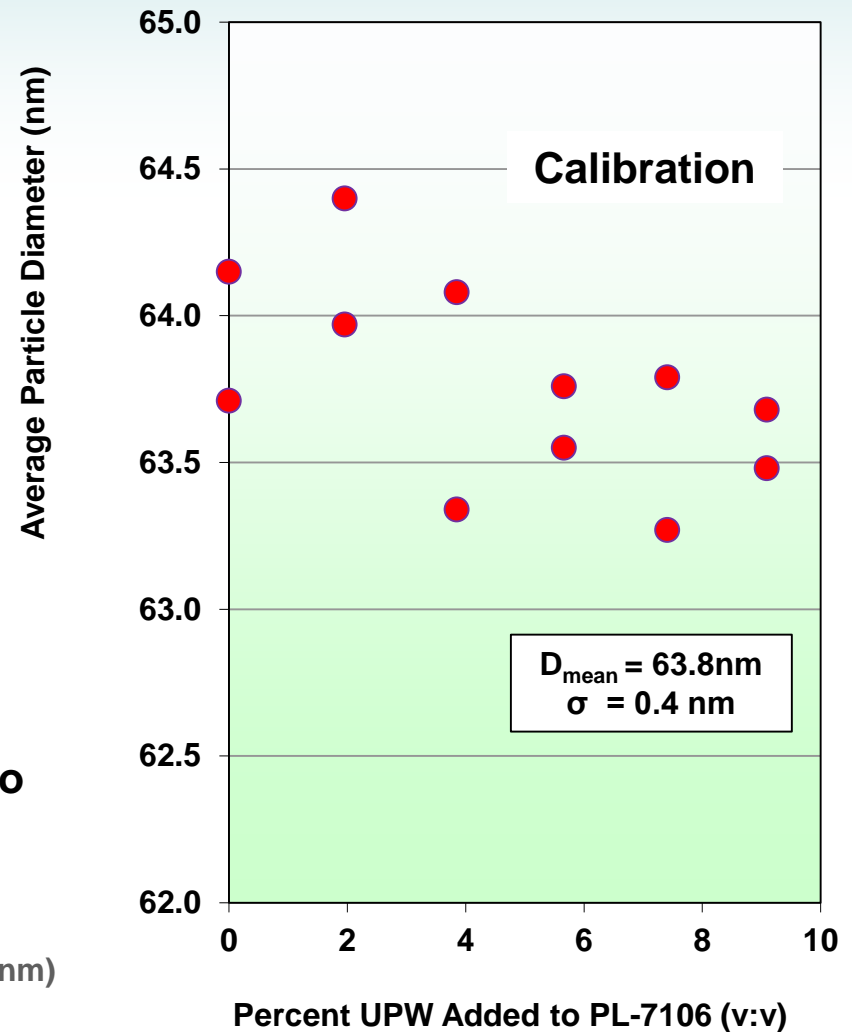
Offline Malvern Zetasizer Nano ZS



- Can analyze samples containing up to 30 weight % solids.
- Gives the “Z-Average” diameter.

$$D_z = \frac{\sum S_i}{\sum \frac{S_i}{D_i}}$$

D_z = Z average diameter (nm)
 S_i = intensity of particle i
 D_i = diameter of particle i (nm)



Phase I – Characterization of Fresh Slurries

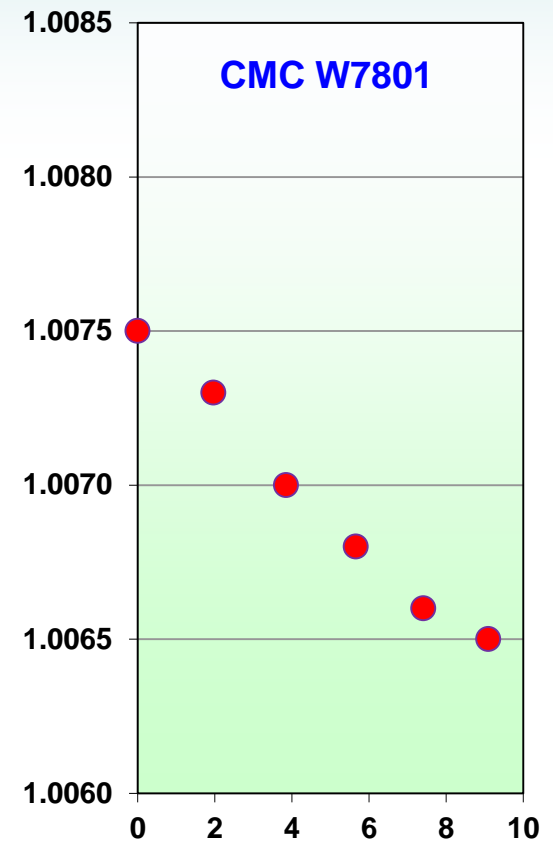
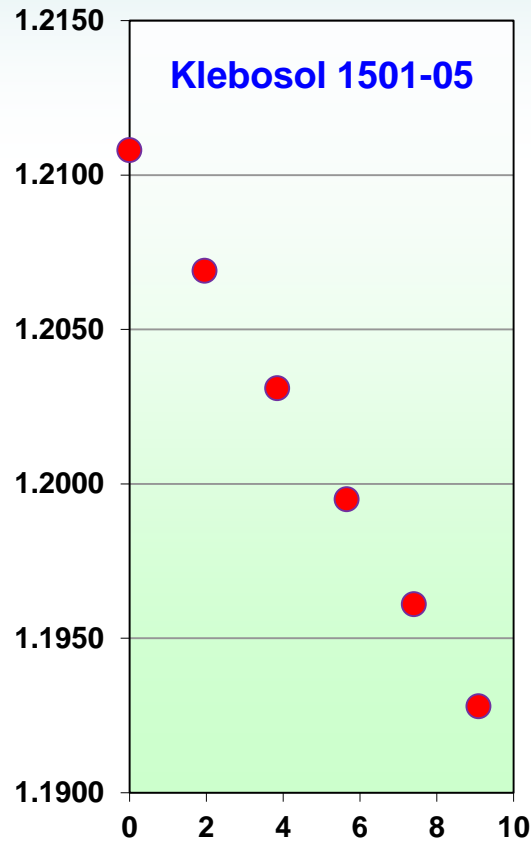
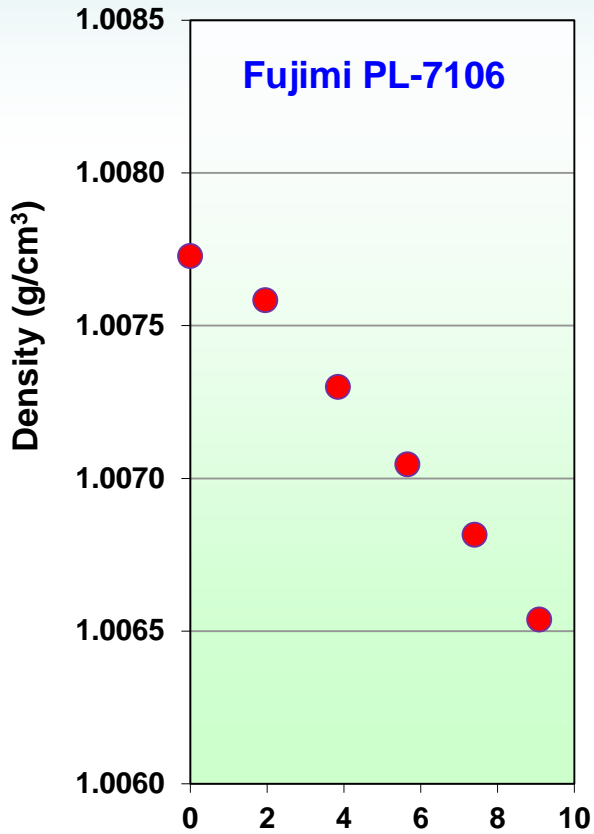
Initial Slurry Preparation

Slurry	Fujimi PL-7106	Klebosol 1501-50	CMC W7801
Manufacturer	Fujimi	Merck	CMC
Application	Copper CMP	ILD CMP	Tungsten CMP
Base Material	Colloidal silica		
Solids Content (%wt)	< 1.5	30.0	< 2.0
Dilution Ratio per Manufacturer's Spec.	UPW:PL-7106:H ₂ O ₂ (30%) 87.0 : 10.2 : 2.8	Use as received (no dilution)	W-7801:H ₂ O ₂ (30%) 97.1 : 2.9

Sample Preparation

Sample	Volume Initial Solution (mL)	Added UPW (mL)	% Added UPW (v:v)
1	1200	0	0.00
2	1200	24	1.96
3	1200	48	3.85
4	1200	78	5.66
5	1200	96	7.41
6	1200	120	9.09

Offline Densitometry



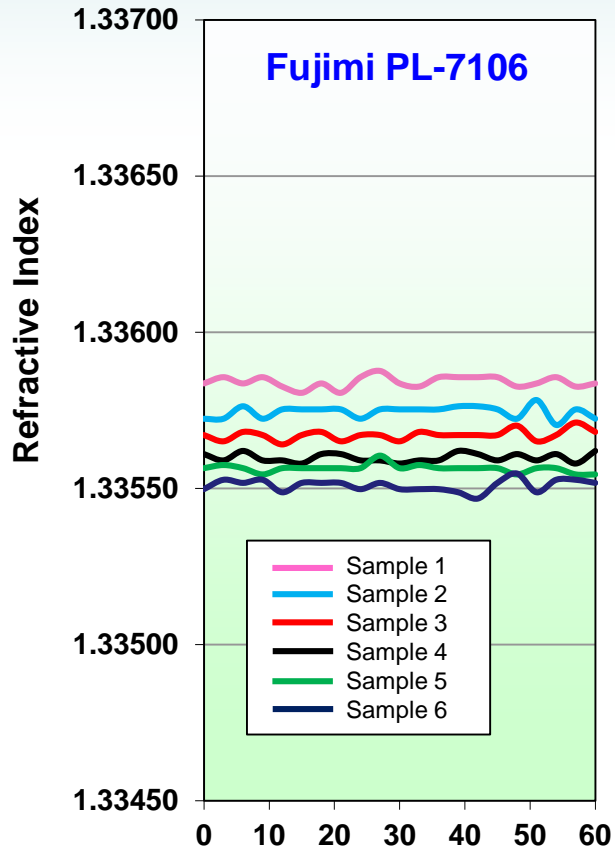
Percent UPW Added (v:v)

$$\text{Slope} = 1.33 \times 10^{-4} \frac{g}{cm^3 \cdot \% UPW}$$

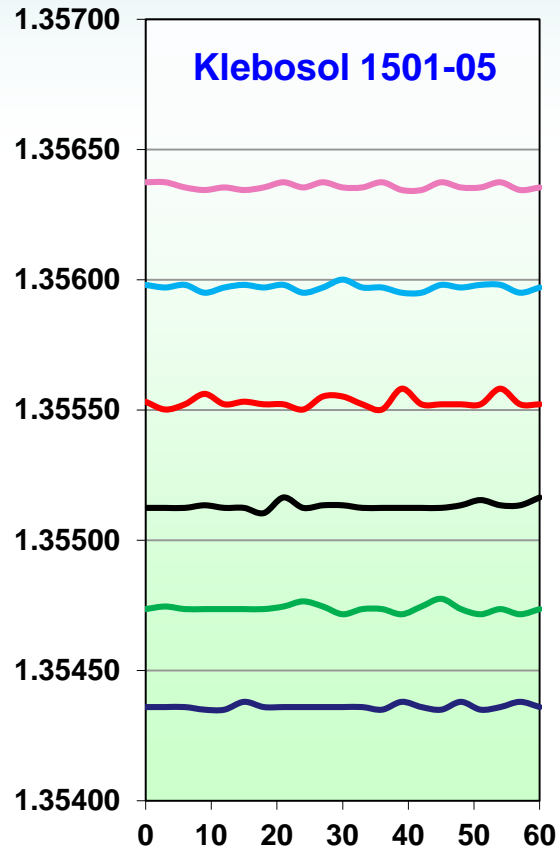
$$\text{Slope} = 1.98 \times 10^{-3} \frac{g}{cm^3 \cdot \% UPW}$$

$$\text{Slope} = 1.15 \times 10^{-4} \frac{g}{cm^3 \cdot \% UPW}$$

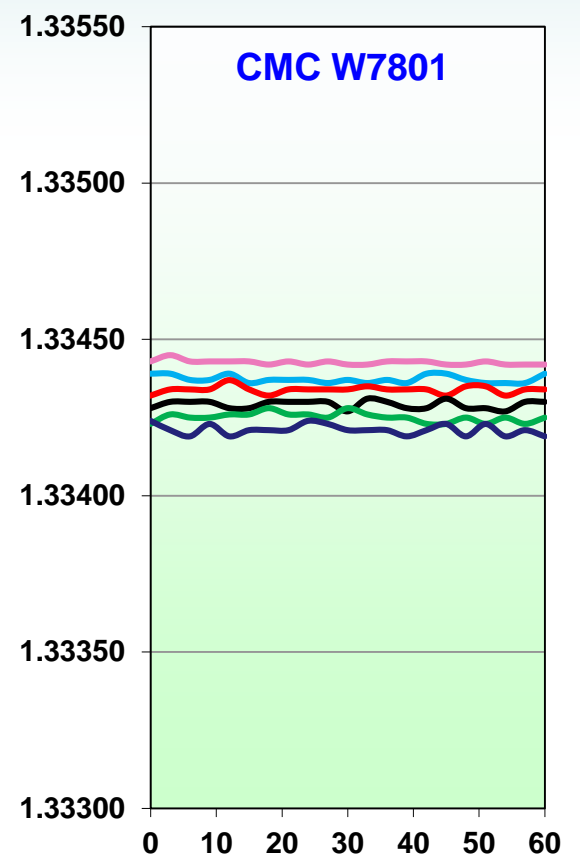
Inline RI



$$\sigma_{\text{avg}} = 1.665 \times 10^{-5}$$

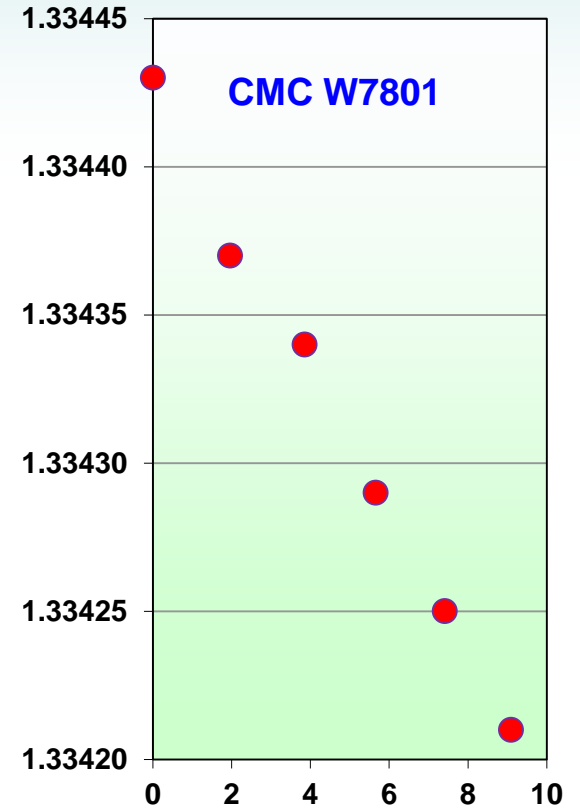
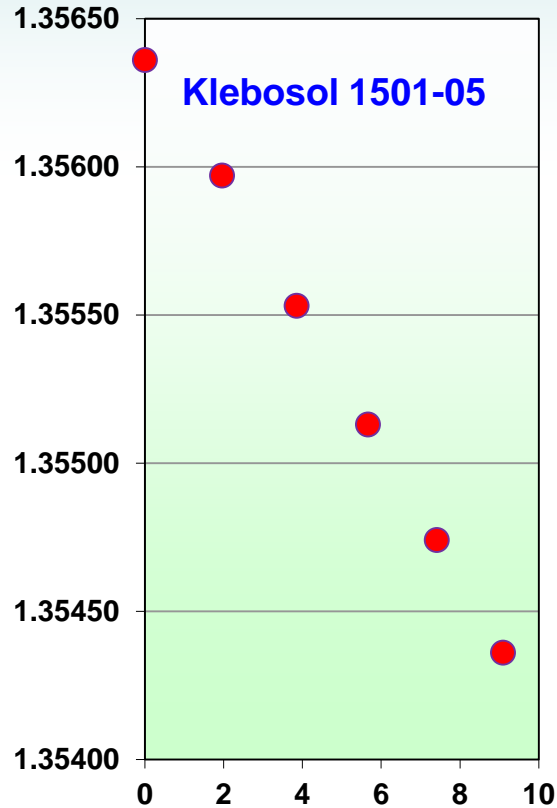
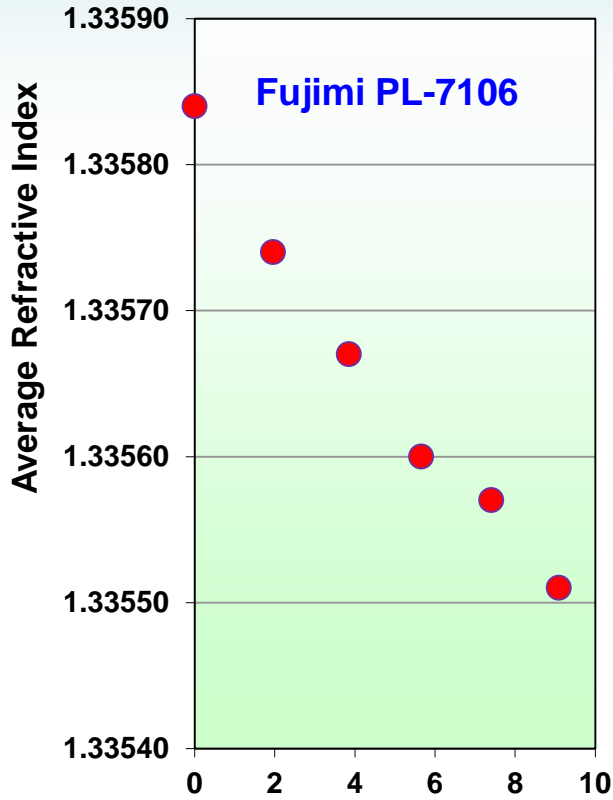


$$\sigma_{\text{avg}} = 1.460 \times 10^{-5}$$



$$\sigma_{\text{avg}} = 1.246 \times 10^{-5}$$

Average RI

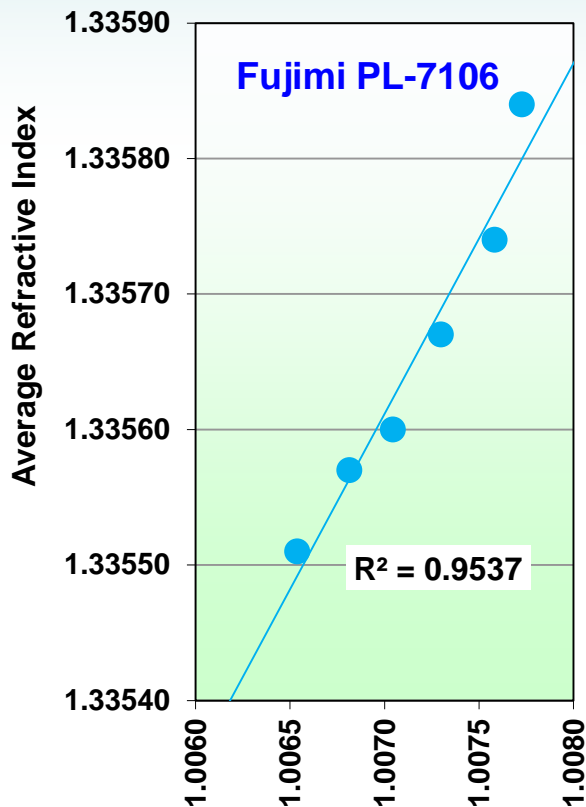


$$\text{Slope} = 3.52 \times 10^{-5} \frac{1}{\% \text{ UPW}}$$

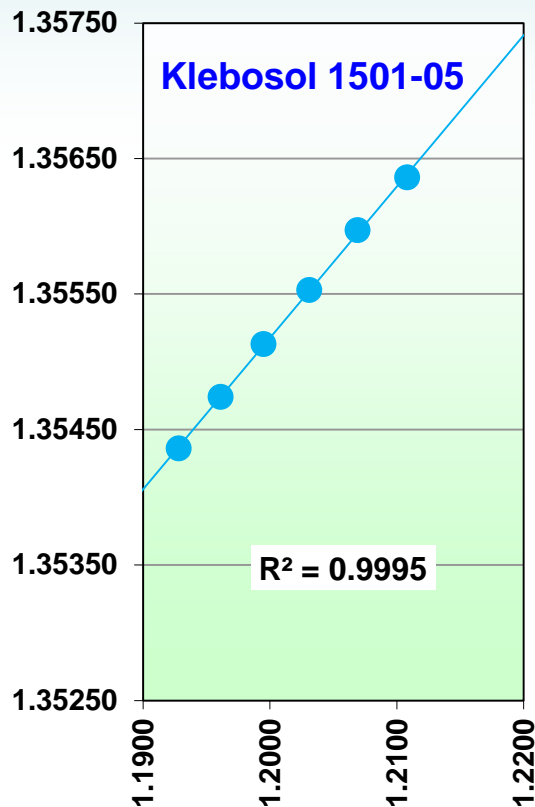
$$\text{Slope} = 2.21 \times 10^{-4} \frac{1}{\% \text{ UPW}}$$

$$\text{Slope} = 2.37 \times 10^{-5} \frac{1}{\% \text{ UPW}}$$

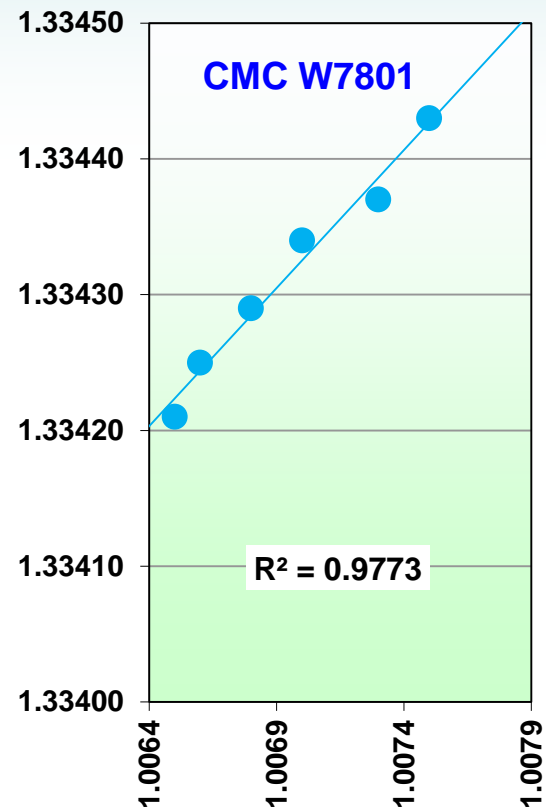
Correlating RI to Density



$d_{\text{mean}} = 68.3 \text{ nm}$
 $\sigma = 0.4 \text{ nm}$



$d_{\text{mean}} = 58.5 \text{ nm}$
 $\sigma = 0.3 \text{ nm}$



$d_{\text{mean}} = 112.8 \text{ nm}$
 $\sigma = 0.7 \text{ nm}$

Correlating RI to Density

Fujimi PL-7106		
	Densitometer	Refractometer
Precision	10^{-4} g/cm^3	10^{-5}
Slope	$1.33 \times 10^{-4} \frac{\text{g}}{\text{cm}^3 \cdot \% \text{ UPW}}$	$3.52 \times 10^{-5} \frac{1}{\% \text{ UPW}}$
LOD (% UPW)	0.752	0.284

Klebosol 1501-05		
	Densitometer	Refractometer
Precision	10^{-4} g/cm^3	10^{-5}
Slope	$1.98 \times 10^{-3} \frac{\text{g}}{\text{cm}^3 \cdot \% \text{ UPW}}$	$2.21 \times 10^{-4} \frac{1}{\% \text{ UPW}}$
LOD (% UPW)	0.050	0.045

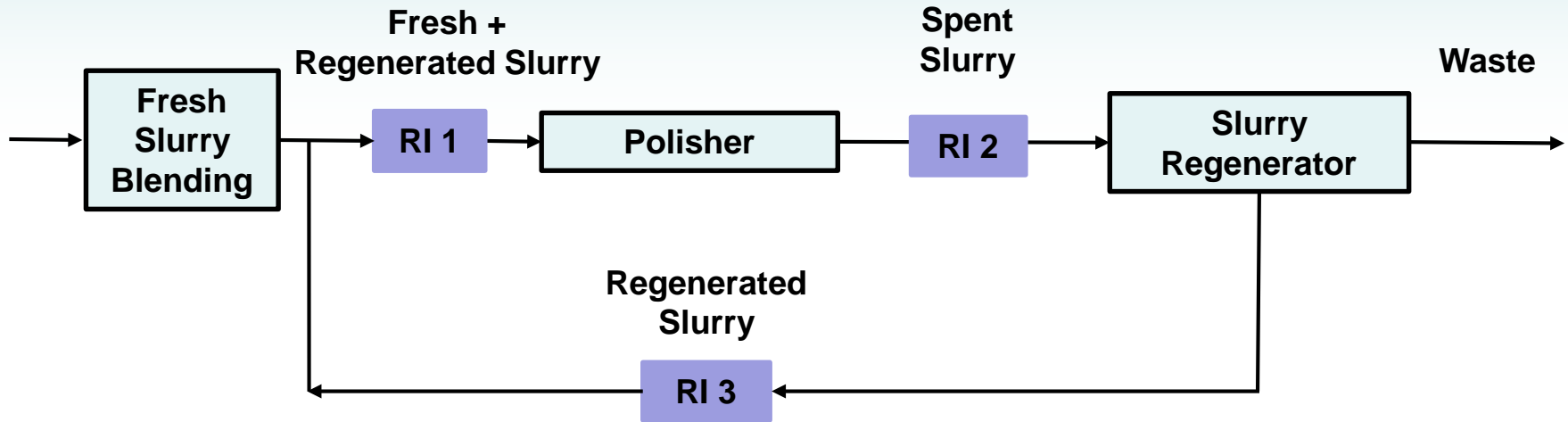
CMC W7801		
	Densitometer	Refractometer
Precision	10^{-4} g/cm^3	10^{-5}
Slope	$1.15 \times 10^{-4} \frac{\text{g}}{\text{cm}^3 \cdot \% \text{ UPW}}$	$2.37 \times 10^{-5} \frac{1}{\% \text{ UPW}}$
LOD (% UPW)	0.870	0.422

Summary of Phase I

- **Fujimi PL-7106, Klebosol 1501-50 and CMC W7801 slurries were successfully characterized via inline RI and offline density measurements.**
- **RI measurement was shown to have a higher precision than densitometry.**
- **Density of the 3 slurries decreased with further addition of UPW. The same was true for RI.**
- **A linear correlation between density and RI was found for the 3 fresh slurries with R^2 values exceeding 0.95.**
- **Compared to density, RI was able to detect smaller changes in incoming slurry concentration, leading to more accurate measurement of slurry composition.**
- **PSD tests showed that UPW dilution did not change average particle size of abrasives thereby further increasing our confidence in the RI data.**

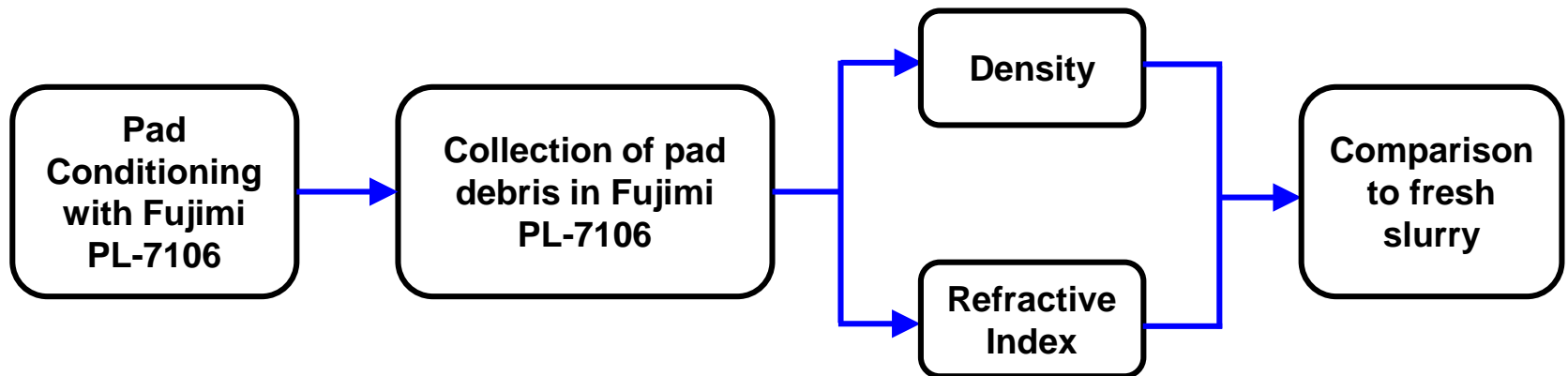
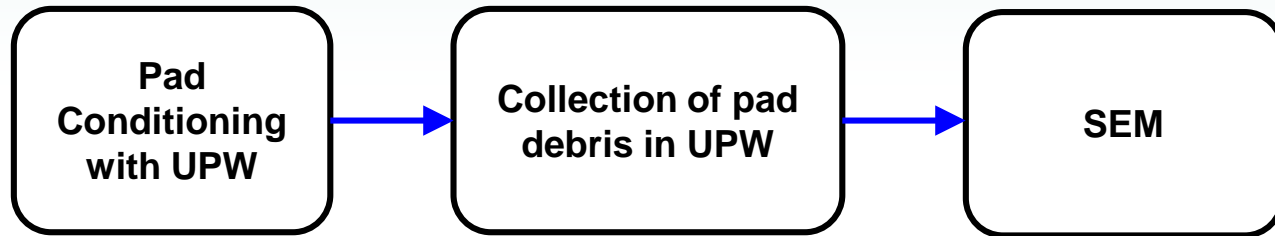
Phase II – Characterization of Spent Fujimi PL-7106 Slurry

Motivation and Goal



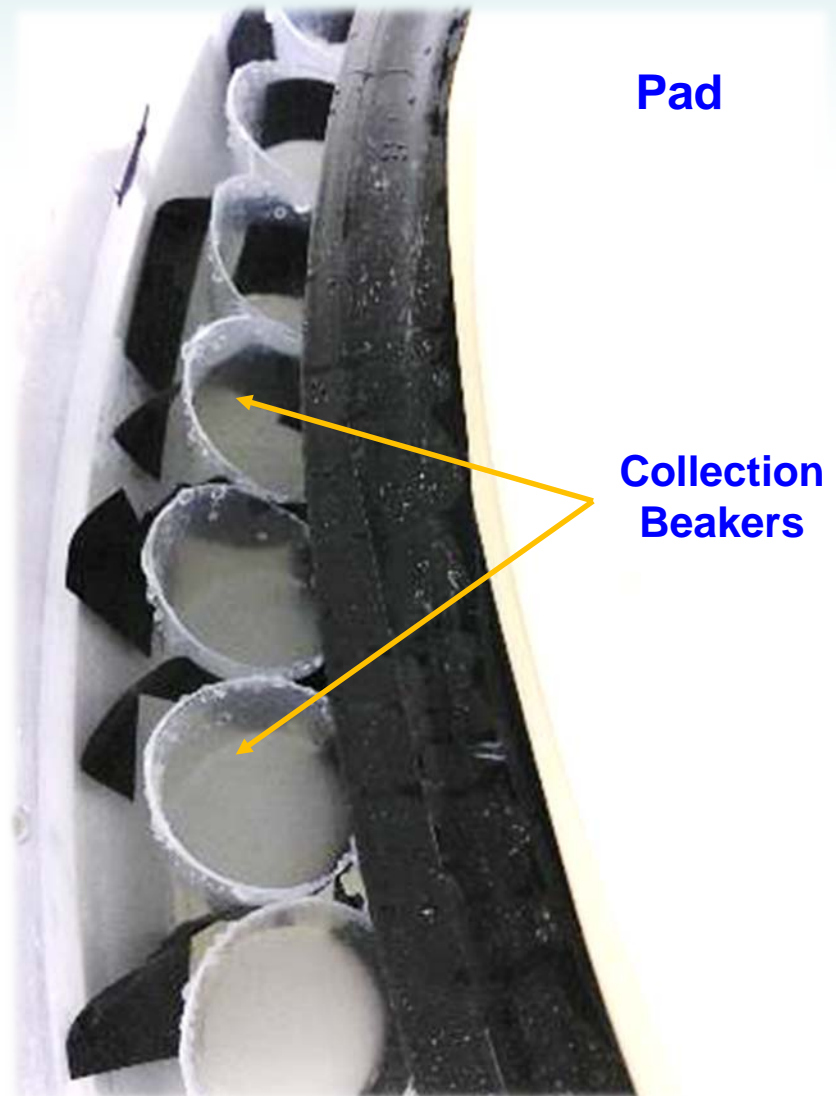
- Slurry waste is one of the main COO and EHS concerns in CMP.
- As such, slurry regeneration and reuse is a potential alternative to decreasing fresh slurry consumption and waste generation.
- However, spent slurry composition and properties must be monitored to have a successful regeneration process.
- One method that can be used to determine pad debris concentration in spent slurry is densitometry.
- **Our goal is to investigate if RI can also indicate (and to a better extent) changes in slurry due to the presence of pad debris.**

Phase II – Flow Chart



Pad Debris Collection

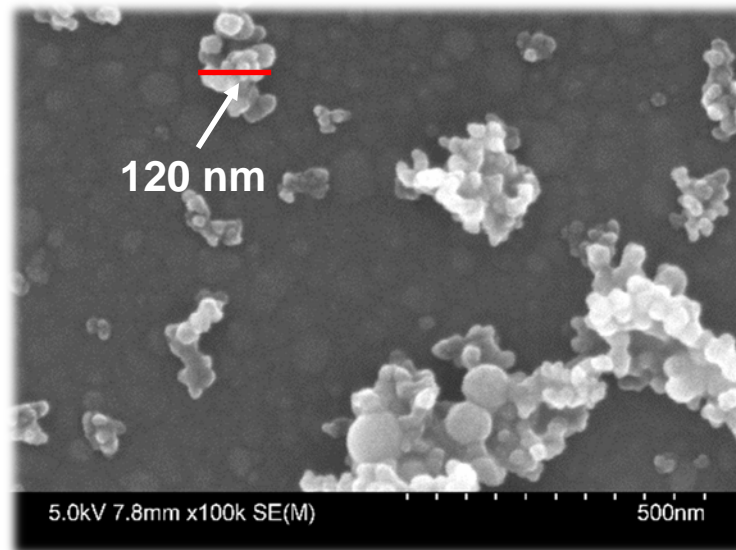
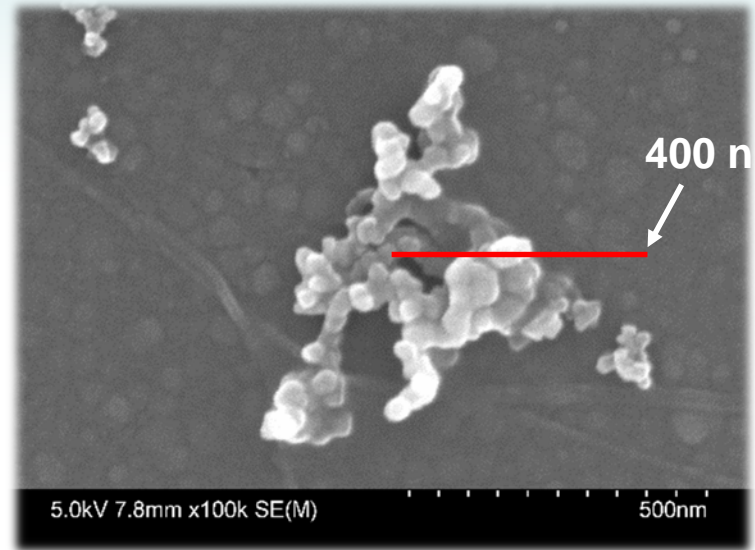
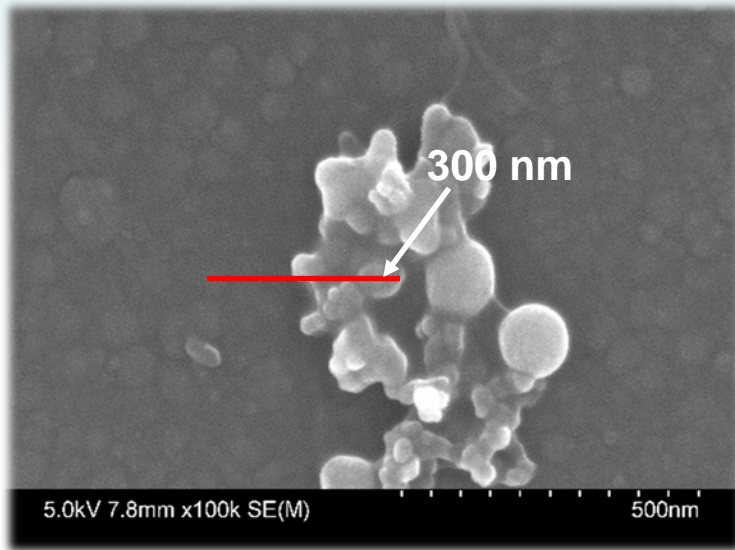
- Samples of UPW (or slurry) containing pad debris are collected during conditioning in the APD-800.
- Collection beakers are placed on the stationary wall past the polisher's splash guard.
- Samples are sonicated for 5 minutes prior to any measurement to ensure suspension homogeneity.



Pad Debris Collection with UPW

- **Dow IC1000 Pad**
 - ❖ Specific gravity = 0.805.
- **UPW**
 - ❖ Flow rate = 250 mL/min.
- **Pad Conditioner**
 - ❖ Abrasive Technology S3410845N
- **Conditioning settings**
 - ❖ Platen rotation rate = 87 RPM.
 - ❖ Disc rotation rate = 60 RPM.
 - ❖ Disc downforce = 10 kg-force.

SEM of Pad Debris



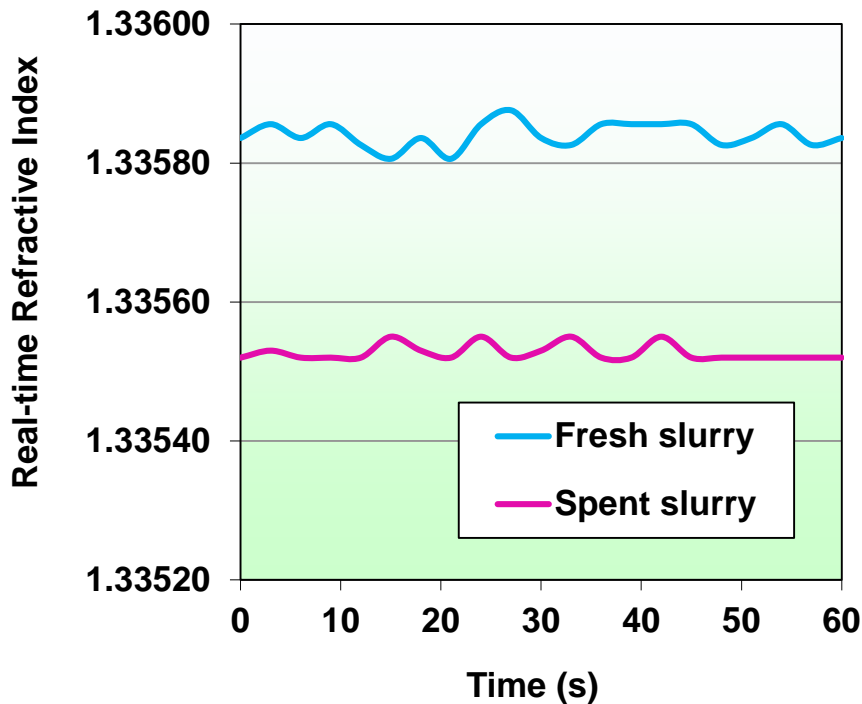
Pad Debris Collection with Slurry

- **Dow IC1000 Pad**
 - ❖ Specific gravity = 0.805.
- **Slurry**
 - ❖ Fujimi PL-7106 with the composition specified in Slide 10.
 - ❖ Flow rate = 250 ml/min
- **Pad Conditioner**
 - ❖ Abrasive Technology S3410845N
- **Conditioning settings**
 - ❖ Platen rotation rate = 87 RPM.
 - ❖ Disc rotation rate = 60 RPM.
 - ❖ Disc downforce = 10 lb-force.

RI and Density Data

	d_c (g/cm ³)
Fresh Slurry	1.0077
Spent Slurry	1.0074

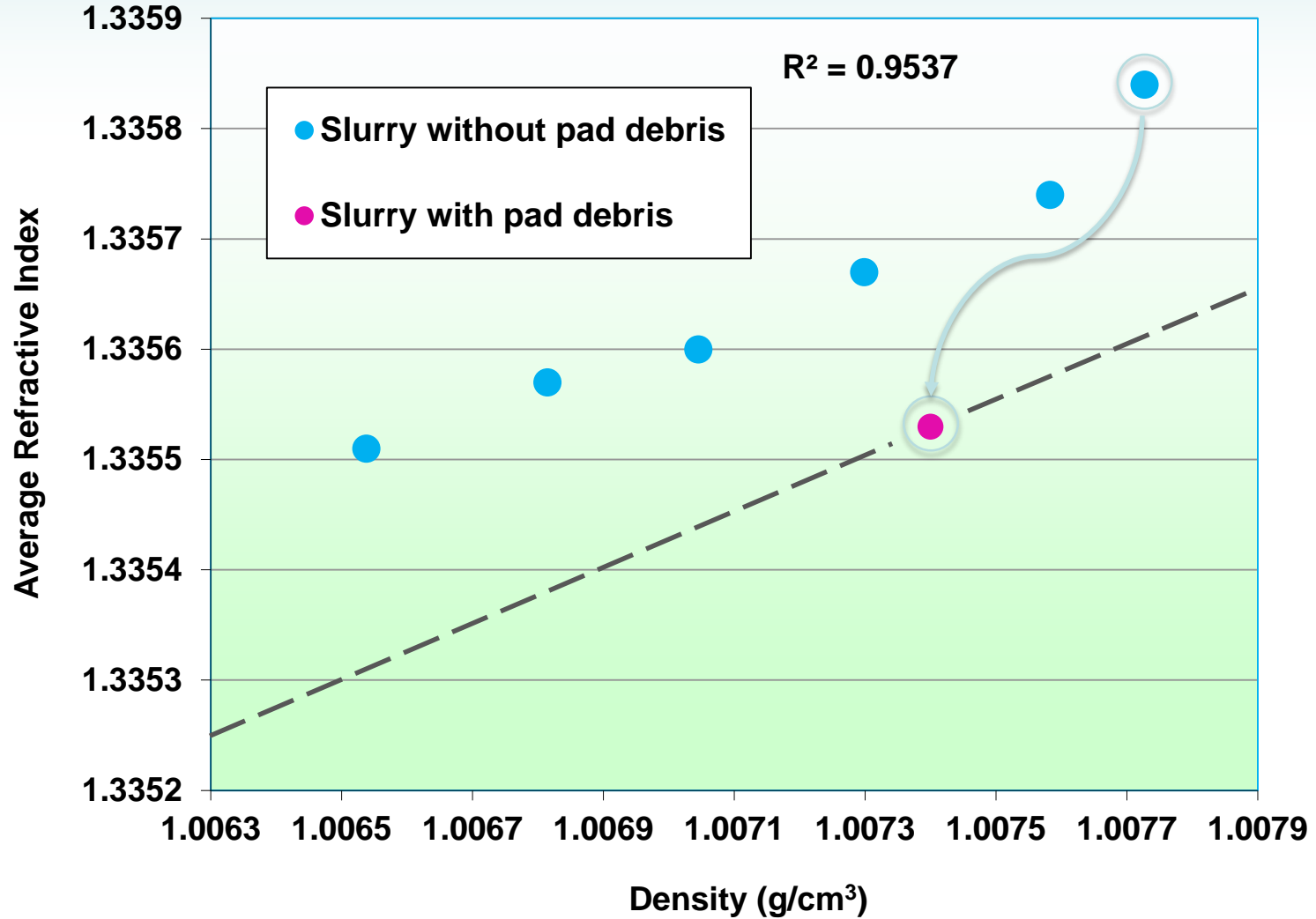
	SG
Fujimi PL-7106	1.00 to 1.08
PU pad	0.805



Pad Debris in Spent Slurry	0.148 % wt
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	Average RI
Fresh Slurry	1.33584
Spent Slurry	1.33553

RI vs. Density Correlation



Summary of Phase II

- The density of undiluted spent PL-7106 was lower than that of undiluted fresh one. This was due to the presence of pad debris (PU with a SG of 0.8).
- The K-Patents refractometer showed that the RI of the spent slurry was also lower than the RI of the fresh slurry.
- As such, the spent slurry **DID NOT** fall on the same correlation curve as the fresh slurry.
- When calibrated properly, RI can be used as an indicator of the presence (and possibly amount) of pad debris in the slurry.
- The Zetasizer Nano ZS was not able to report silica and polyurethane particle sizes independently. This was due to similar values of RI for silica and PU.

Thank You!